

# Nong-Moon Hwang

## List of Publications by Year in descending order

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101  
papers

1,729  
citations

361413

20  
h-index

330143

37  
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104  
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104  
docs citations

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times ranked

1238  
citing authors

#	ARTICLE	IF	CITATIONS
1	Insulation Coating of Fe <sub>3</sub> SiCr Soft Magnetic Powder by Selective Oxidation. <i>Metals and Materials International</i> , 2022, 28, 1778-1782.	3.4	3
2	Non-classical Crystallization of Bulk Crystals in Solution and of Thin Films in the Gas Phase by Chemical Vapor Deposition. <i>Electronic Materials Letters</i> , 2022, 18, 1-26.	2.2	4
3	Effects of Sputtering Power, Working Pressure, and Electric Bias on the Deposition Behavior of Ag Films during DC Magnetron Sputtering Considering the Generation of Charged Flux. <i>Electronic Materials Letters</i> , 2022, 18, 57-68.	2.2	1
4	Effects of Electrostatic Interaction on the Formation of a Particle Depletion Zone by Charged Nanoparticles during the Chemical Vapor Deposition of Si Processes. <i>Crystal Growth and Design</i> , 2022, 22, 2490-2498.	3.0	1
5	Generation of positively charged nanoparticles by fracto-emission and their deposition into films during aerosol deposition. <i>Applied Surface Science</i> , 2022, 593, 153466.	6.1	3
6	Misorientation Characteristics at the Growth Front of Abnormally-Growing Goss Grains in Fe-3%Si Steel. <i>Metals and Materials International</i> , 2021, 27, 5114-5120.	3.4	4
7	Phonon spectra of clean and Ni-terminated diamond (111) surfaces: An ab-initio study. <i>Current Applied Physics</i> , 2021, 21, 134-139.	2.4	1
8	Unusual Dependence of the Diamond Growth Rate on the Methane Concentration in the Hot Filament Chemical Vapor Deposition Process. <i>Materials</i> , 2021, 14, 426.	2.9	5
9	Dependence of the Generation Behavior of Charged Nanoparticles and Ag Film Growth on Sputtering Power during DC Magnetron Sputtering. <i>Electronic Materials Letters</i> , 2021, 17, 172-180.	2.2	6
10	Comparison of diamond nanoparticles captured on the floating and grounded membranes in the hot filament chemical vapor deposition process. <i>RSC Advances</i> , 2021, 11, 5651-5657.	3.6	8
11	Effect of Pressure on the Film Deposition during RF Magnetron Sputtering Considering Charged Nanoparticles. <i>Coatings</i> , 2021, 11, 132.	2.6	6
12	Charging Effects on the Adsorption and Diffusion of Au Adatoms on MgO(100). <i>Journal of the Physical Society of Japan</i> , 2021, 90, 034602.	1.6	4
13	Two-Step Deposition of Silicon Oxide Films Using the Gas Phase Generation of Nanoparticles in the Chemical Vapor Deposition Process. <i>Coatings</i> , 2021, 11, 365.	2.6	1
14	Ab-initio study of the effects of charging on the adsorption and diffusion of Au <sub>2</sub> on MgO(100). <i>Current Applied Physics</i> , 2021, 24, 39-45.	2.4	4
15	Effect of the Dispersion State in Y <sub>2</sub> O <sub>3</sub> Suspension on YOF Coating Deposited by Suspension Plasma Spray. <i>Coatings</i> , 2021, 11, 831.	2.6	3
16	Importance of Interfacial Structures in the Catalytic Effect of Transition Metals on Diamond Growth. <i>ACS Omega</i> , 2021, 6, 28432-28440.	3.5	2
17	Nonclassical Crystallization of an Al <sub>2</sub> O <sub>3</sub> Film by Positively Charged Secondary Nanoparticles during Aerosol Deposition. <i>Crystal Growth and Design</i> , 2021, 21, 7240-7246.	3.0	4
18	Preparation of Highly (002) Oriented Ti Films on a Floating Si (100) Substrate by RF Magnetron Sputtering. <i>Electronic Materials Letters</i> , 2020, 16, 14-21.	2.2	8

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19	Comparison of Plasma Effect on Dewetting Kinetics of Sn Films Between Grounded and Floating Substrates. <i>Electronic Materials Letters</i> , 2020, 16, 72-80.	2.2	15
20	Generation of Charged SiC Nanoparticles During HWCVD Process. <i>Electronic Materials Letters</i> , 2020, 16, 498-505.	2.2	10
21	Plasma Etching Behavior of YOF Coating Deposited by Suspension Plasma Spraying in Inductively Coupled CHF <sub>3</sub> /Ar Plasma. <i>Coatings</i> , 2020, 10, 1023.	2.6	13
22	Effects of the Size of Charged Nanoparticles on the Crystallinity of SiC Films Prepared by Hot Wire Chemical Vapor Deposition. <i>Coatings</i> , 2020, 10, 726.	2.6	2
23	The Effect of Charged Ag Nanoparticles on Thin Film Growth during DC Magnetron Sputtering. <i>Coatings</i> , 2020, 10, 736.	2.6	4
24	Various Allotropes of Diamond Nanoparticles Generated in the Gas Phase during Hot Filament Chemical Vapor Deposition. <i>Nanomaterials</i> , 2020, 10, 2504.	4.1	9
25	Generation of Charged Ti Nanoparticles and Their Deposition Behavior with a Substrate Bias during RF Magnetron Sputtering. <i>Coatings</i> , 2020, 10, 443.	2.6	7
26	Ex-Situ Time Sequential Observation on Island and Peninsular Grains in Abnormally Growing Goss Grains in Fe-3%Si Steel. <i>Metals and Materials International</i> , 2020, 26, 1200-1206.	3.4	6
27	Effect of Bipolar Charging of SiH <sub>4</sub> on the Growth Rate and Crystallinity of Silicon Films Grown in the Atmospheric Pressure Chemical Vapor Deposition Process. <i>Electronic Materials Letters</i> , 2020, 16, 385-395.	2.2	7
28	Yttrium Oxyfluoride Coatings Deposited by Suspension Plasma Spraying Using Coaxial Feeding. <i>Coatings</i> , 2020, 10, 481.	2.6	10
29	Beyond carbon-solvency effects of catalytic metal Ni on diamond growth. <i>Diamond and Related Materials</i> , 2020, 107, 107875.	3.9	3
30	Formation of Pentagonal Dimples in Icosahedral Diamond Crystals Grown by Hot Filament Chemical Vapor Deposition: Approach by Non-Classical Crystallization. <i>Coatings</i> , 2019, 9, 269.	2.6	1
31	Deposition Behavior of Boron-Doped Diamond with Varying Amount of Acetone by Hot Filament Chemical Vapor Deposition. <i>Electronic Materials Letters</i> , 2019, 15, 630-638.	2.2	5
32	Effect of Pulsed Electric Current on TRIP-Aided Steel. <i>International Journal of Precision Engineering and Manufacturing - Green Technology</i> , 2019, 6, 315-327.	4.9	18
33	Effects of radio frequency power and gas ratio on barrier properties of SiO <sub>x</sub> N <sub>y</sub> films deposited by inductively coupled plasma chemical vapor deposition. <i>Thin Solid Films</i> , 2019, 669, 108-113.	1.8	6
34	Synthesis of nanostructures using charged nanoparticles spontaneously generated in the gas phase during chemical vapor deposition. <i>Journal Physics D: Applied Physics</i> , 2018, 51, 463002.	2.8	14
35	Effect of Asymmetric Hot Rolling on the Texture Evolution of Fe-3%Si Steel. <i>Metals and Materials International</i> , 2018, 24, 1369-1375.	3.4	5
36	Computer Simulation of Temperature Parameter for Diamond Formation by Using Hot-Filament Chemical Vapor Deposition. <i>Coatings</i> , 2018, 8, 15.	2.6	10

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37	Effect of Bias Applied to the Substrate on the Low Temperature Growth of Silicon Epitaxial Films during RF-PECVD. <i>Crystal Growth and Design</i> , 2018, 18, 5816-5823.	3.0	14
38	Fabrication of Highly Transparent and Cost-Effective Soda Lime Glass with Antireflective Nanostructures Using Silver Ink. <i>Physica Status Solidi (A) Applications and Materials Science</i> , 2018, 215, 1700949.	1.8	0
39	Effect of the substrate bias in diamond deposition during hot filament chemical vapor deposition: Approach by non-classical crystallization. <i>Advanced Materials Letters</i> , 2018, 9, 638-642.	0.6	3
40	Effect of substrate bias on deposition behaviour of charged silicon nanoparticles in ICP-CVD process. <i>Journal Physics D: Applied Physics</i> , 2017, 50, 035201.	2.8	11
41	Simultaneous increase in strength and ductility by decreasing interface energy between Zn and Al phases in cast Al-Zn-Cu alloy. <i>Scientific Reports</i> , 2017, 7, 12195.	3.3	7
42	Control of nanoparticle size and amount by using the mesh grid and applying DC-bias to the substrate in silane ICP-CVD process. <i>Journal of Nanoparticle Research</i> , 2017, 19, 1.	1.9	8
43	Non-classical crystallization of silicon thin films during hot wire chemical vapor deposition. <i>Journal of Crystal Growth</i> , 2017, 458, 8-15.	1.5	15
44	Low temperature deposition of polycrystalline silicon thin films on a flexible polymer substrate by hot wire chemical vapor deposition. <i>Journal of Crystal Growth</i> , 2016, 453, 151-157.	1.5	10
45	Gas phase generation of diamond nanoparticles in the hot filament chemical vapor deposition reactor. <i>Carbon</i> , 2016, 106, 289-294.	10.3	30
46	Alignment of nanoparticles, nanorods, and nanowires during chemical vapor deposition of silicon. <i>Applied Physics A: Materials Science and Processing</i> , 2015, 120, 889-895.	2.3	4
47	New understanding of the role of coincidence site lattice boundaries in abnormal grain growth of aluminium alloy. <i>Philosophical Magazine Letters</i> , 2015, 95, 220-228.	1.2	6
48	Effect of Electric Bias on the Deposition Behavior of ZnO Nanostructures in the Chemical Vapor Deposition Process. <i>Journal of Physical Chemistry C</i> , 2015, 119, 25047-25052.	3.1	20
49	Structural and optical properties of H <sub>2</sub> diluted c-Si/a-SiO <sub>x</sub> core-shell silicon nanowire. <i>Applied Physics A: Materials Science and Processing</i> , 2015, 118, 269-274.	2.3	3
50	Nonclassical Crystallization in Low-Temperature Deposition of Crystalline Silicon by Hot-Wire Chemical Vapor Deposition. <i>Crystal Growth and Design</i> , 2014, 14, 6239-6247.	3.0	8
51	Comparison of the Deposition Behavior of Charged Silicon Nanoparticles between Floating and Grounded Substrates. <i>Journal of Physical Chemistry C</i> , 2014, 118, 11946-11953.	3.1	25
52	Formation and development of dislocation in graphene. <i>Applied Physics Letters</i> , 2013, 102, .	3.3	31
53	Effect of HCl addition on the properties of p-type silicon thin films during hot-wire chemical vapor deposition. <i>Renewable Energy</i> , 2013, 54, 85-90.	8.9	4
54	Effect of the Carrier Gas Flow Rate on the Microstructure Evolution and the Generation of the Charged Nanoparticles During Silicon Chemical Vapor Deposition. <i>Journal of Nanoscience and Nanotechnology</i> , 2013, 13, 7127-7130.	0.9	7

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55	Parallel three-dimensional Monte Carlo simulations for effects of precipitates and sub-boundaries on abnormal grain growth of Goss grains in Fe-3%Si steel. <i>Philosophical Magazine</i> , 2013, 93, 4198-4212.	1.6	10
56	In-Situ Measurements of Charged Nanoparticles Generated During Hot Wire Chemical Vapor Deposition of Silicon Using Particle Beam Mass Spectrometer. <i>Aerosol Science and Technology</i> , 2013, 47, 46-51.	3.1	11
57	Formation of Tetrapod-Shaped Nanowires in the Gas Phase During the Synthesis of ZnO Nanostructures by Carbothermal Reduction. <i>Journal of Nanoscience and Nanotechnology</i> , 2013, 13, 7198-7201.	0.9	5
58	Effect of the Initial Structure on the Electrical Property of Crystalline Silicon Films Deposited on Glass by Hot-Wire Chemical Vapor Deposition. <i>Journal of Nanoscience and Nanotechnology</i> , 2012, 12, 5947-5951.	0.9	6
59	Irregular or Smooth Grain Boundaries Evolved after Secondary Recrystallization of Fe-3%Si Steel. <i>Materials Transactions</i> , 2012, 53, 658-661.	1.2	5
60	Generation of Charged Nanoparticles and Their Deposition Behavior under Alternating Electric Bias during Chemical Vapor Deposition of Silicon. <i>Journal of Physical Chemistry C</i> , 2012, 116, 25157-25163.	3.1	7
61	Abnormal grain growth in the nanostructured Invar alloy fabricated by electrodeposition. <i>Philosophical Magazine Letters</i> , 2012, 92, 589-596.	1.2	2
62	Ex Situ Observation of Microstructure Evolution During Abnormal Grain Growth in Aluminum Alloy. <i>Metallurgical and Materials Transactions A: Physical Metallurgy and Materials Science</i> , 2012, 43, 5218-5223.	2.2	14
63	Generation of Charged Nanoparticles During the Synthesis of GaN Nanostructures by Atmospheric-Pressure Chemical Vapor Deposition. <i>Aerosol Science and Technology</i> , 2012, 46, 1100-1108.	3.1	12
64	Reduction of amorphous incubation layer by HCl addition during deposition of microcrystalline silicon by hot-wire chemical vapor deposition. <i>Solar Energy Materials and Solar Cells</i> , 2011, 95, 211-214.	6.2	16
65	Deformation Feature of Goss Grains in Fe-3%Si Steel Focused on Stored Energy after Cold Rolling. <i>Materials Transactions</i> , 2010, 51, 1547-1552.	1.2	8
66	Generation of Charged Nanoparticles During the Synthesis of Silicon Nanowires by Chemical Vapor Deposition. <i>Journal of Physical Chemistry C</i> , 2010, 114, 3390-3395.	3.1	21
67	Charged nanoparticles in thin film and nanostructure growth by chemical vapour deposition. <i>Journal of Physics D: Applied Physics</i> , 2010, 43, 483001.	2.8	52
68	The role of pentagon-heptagon pair defect in carbon nanotube: The center of vacancy reconstruction. <i>Applied Physics Letters</i> , 2010, 97, 093106.	3.3	15
69	Reconstruction and evaporation at graphene nanoribbon edges. <i>Physical Review B</i> , 2010, 81, .	3.2	55
70	Generation of charged nanoparticles and their deposition during the synthesis of silicon thin films by chemical vapor deposition. <i>Journal of Applied Physics</i> , 2010, 108, 014313.	2.5	16
71	Generation of Charged Nanoparticles during Synthesis of ZnO Nanowires by Carbothermal Reduction. <i>Aerosol Science and Technology</i> , 2009, 43, 120-125.	3.1	26
72	Generation of charged nanoparticles during the synthesis of carbon nanotubes by chemical vapor deposition. <i>Carbon</i> , 2009, 47, 2511-2518.	10.3	30

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73	Equilibrium shape of nickel crystal. Philosophical Magazine, 2009, 89, 2989-2999.	1.6	16
74	Comparison of the Advantages Conferred by Mobility and Energy of the Grain Boundary in Inducing Abnormal Grain Growth Using Monte Carlo Simulations. Materials Transactions, 2009, 50, 2521-2525.	1.2	16
75	Generation of negative-charge carriers in the gas phase and their contribution to the growth of carbon nanotubes during hot-filament chemical vapor deposition. Carbon, 2008, 46, 1588-1592.	10.3	21
76	The formation of pentagon-heptagon pair defect by the reconstruction of vacancy defects in carbon nanotube. Applied Physics Letters, 2008, 92, 043104.	3.3	33
77	Formation of carbon nanotube semiconductor-metal intramolecular junctions by self-assembly of vacancy defects. Physical Review B, 2007, 76, .	3.2	32
78	Reply to the Comment on "Effect of Interface Structure on the Microstructural Evolution of Ceramics". Journal of the American Ceramic Society, 2007, 90, 2293-2295.	3.8	4
79	Vacancy defects and the formation of local haeckelite structures in graphene from tight-binding molecular dynamics. Physical Review B, 2006, 74, .	3.2	81
80	Abnormal Grain Growth of Lead Zirconium Titanate (PZT) Ceramics Induced by the Penetration Twin. Journal of the American Ceramic Society, 2006, 89, 1530-1533.	3.8	8
81	Effect of Interface Structure on the Microstructural Evolution of Ceramics. Journal of the American Ceramic Society, 2006, 89, 2369-2380.	3.8	132
82	Spontaneous generation of negatively charged clusters and their deposition as crystalline films during hot-wire silicon chemical vapor deposition. Pure and Applied Chemistry, 2006, 78, 1715-1722.	1.9	25
83	Effect of SiO <sub>2</sub> and TiO <sub>2</sub> Addition on the Morphology of Abnormally Grown Large Pb(Mg <sub>1/3</sub> Nb <sub>2/3</sub> )O <sub>3-35</sub> mol% PbTiO <sub>3</sub> Grains. Journal of the American Ceramic Society, 2005, 88, 1992-1994.	3.8	7
84	Three-dimensional simulation of microstructure evolution in damascene interconnects: Effect of overburden thickness. Journal of Electronic Materials, 2005, 34, 559-563.	2.2	10
85	Effect of substrate materials in the low-pressure synthesis of diamond: approach by theory of charged clusters. International Journal of Materials Research, 2005, 96, 225-232.	0.8	9
86	Coarsening Process of Penetration-Induced Twinned Grains in PMN-35 mol% PT Ceramics. Journal of the American Ceramic Society, 2004, 87, 125-128.	3.8	10
87	Abnormal Grain Growth Occurring at the Surface of a Sintered BaTiO <sub>3</sub> Specimen. Journal of the American Ceramic Society, 2004, 87, 1779-1781.	3.8	16
88	First-principles study of the effect of charge on the stability of a diamond nanocluster surface. Physical Review B, 2004, 69, .	3.2	14
89	Charged clusters in thin film growth. International Materials Reviews, 2004, 49, 171-190.	19.3	68
90	Effect of the Liquid-Forming Additive Content on the Kinetics of Abnormal Grain Growth in Alumina. Journal of the American Ceramic Society, 2003, 86, 1421-1423.	3.8	54

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91	Characteristics of Liquid Penetration into Undoped and Magnesia- $\delta$ -Doped Alumina. Journal of the American Ceramic Society, 2003, 86, 2206-2208.	3.8	0
92	Effect of grain boundary energy on surface-energy induced abnormal grain growth in columnar-grained film. Metals and Materials International, 2002, 8, 1-5.	3.4	8
93	Effect of Grain Coalescence on the Abnormal Grain Growth of $\text{Pb}(\text{Mg}_{1/3}\text{Nb}_{2/3})\text{O}_3$ $\approx$ 35 mol% $\text{PbTiO}_3$ Ceramics. Journal of the American Ceramic Society, 2002, 85, 965-968.	3.8	24
94	Abnormal Grain Growth of $\text{Pb}(\text{Mg}_{1/3}\text{Nb}_{2/3})\text{O}_3$ $\approx$ 35 mol% $\text{PbTiO}_3$ Ceramics Induced by the Penetration Twin. Journal of the American Ceramic Society, 2002, 85, 3076-3080.	3.8	9
95	Pore- $\delta$ -Boundary Separation Behavior during Sintering of Pure and $\text{Bi}_2\text{O}_3$ - $\delta$ -Doped $\text{ZnO}$ Ceramics. Journal of the American Ceramic Society, 2001, 84, 1398-1400.	3.8	21
96	Grain boundary faceting and abnormal grain growth in nickel. Metallurgical and Materials Transactions A: Physical Metallurgy and Materials Science, 2000, 31, 985-994.	2.2	14
97	Grain boundary faceting and abnormal grain growth in nickel. Metallurgical and Materials Transactions A: Physical Metallurgy and Materials Science, 2000, 31, 985-994.	2.2	103
98	Abnormal growth of faceted (WC) grains in a (Co) liquid matrix. Metallurgical and Materials Transactions A: Physical Metallurgy and Materials Science, 1996, 27, 2809-2819.	2.2	232
99	Misorientation characteristics of penetrating morphologies at the growth front of abnormally growing grains in aluminum alloy. Philosophical Magazine Letters, 0, , 1-8.	1.2	2
100	Effect of Cooling Rate on Phase Transformation Behavior during Isothermal Annealing of SCr420 Steel. Steel Research International, 0, , 2100711.	1.8	2
101	Yttrium Oxyfluoride Coating Deposited with a $\text{Y}_5\text{O}_4\text{F}_7/\text{YF}_3$ Suspension by Suspension Plasma Spraying Under Atmospheric Pressure. Journal of Thermal Spray Technology, 0, , 1.	3.1	2